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Application No.: 10/603,924

Docket No.: JCLA7109-R

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re APPLICATION of

	Shiao-Chung Hu)	
)	Examiner : Nguyen, Thanh T.
Serial No. :	10/603,924)	
)	Art Unit : 2813
Filed :	June 24 th , 2003)	
)	Docket No. : JCLA7109-R
For :	POST-CMP REMOVAL OF SURFACE)		
	CONTAMINATS FROM SILICON)		
	WAFER)	

AMENDMENT AND RESPONSE TO OFFICE ACTION

Mail Stop Amendment
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The Office Action mailed July 11th, 2006 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.

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